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IN THE CLAIMS

--1. (Twice Amended) An optical disk substrate film-formation apparatus which manufactures an optical disk by forming a thin film on the surface of a substrate, said apparatus comprising:

a substrate holder which fixes said substrate during the formation of said film, wherein said substrate holder [has] <u>includes</u>,

a contact holding surface contacting at least a portion of a rear surface of a filmformed area of said substrate on which said film is formed, [and]

a vacuum chuck section for adsorbing and fixing said contact holding surface to said substrate, and

a removal claw having an inclined section configured to go into a section between a rear surface of the substrate and a top surface of the substrate holder to mechanically peel off the adsorbed substrate from the substrate holder

[wherein said contact holding surface is substantially planar with a top surface of said substrate holder].

6. (Twice Amended) An optical disk substrate film-formation apparatus which manufactures an optical disk by forming a thin film on the surface of a substrate, said apparatus comprising:

a substrate holder which fixes said substrate during the formation of said film, wherein said substrate has a thickness of 0.6 mm or less, and wherein said substrate holder [has] includes.

a contact holding surface contacting at least a portion of a rear surface of a film-formed area of said substrate on which said film is formed, [and]

a vacuum chuck section for adsorbing and fixing said contact holding surface to said substrate, and

a removal claw having an inclined section configured to go into a section between a rear surface of the substrate and a top surface of the substrate holder to mechanically peel off the adsorbed substrate from the substrate holder

[wherein said contact holding surface is substantially planar with a top surface of said substrate holder].

11. (Twice Amended) An optical disk substrate film-formation apparatus comprising:

a substrate holder which holds a substrate at its rear surface so that sputter film formation can be carried out on the front surface of said substrate,

wherein said substrate holder [having] includes.

a substrate holding surface which comes in contact with said rear surface of said substrate,

a vacuum chuck section for adsorbing and fixing said contact holding surface to said substrate, and

a removal claw having an inclined section configured to go into a section between a rear surface of the substrate and a top surface of the substrate holder to mechanically peel off the adsorbed substrate from the substrate holder.

[wherein an entire surface of said substrate holding surface contacting said rear surface is rough].

15. (Twice Amended) An optical disk substrate film-formation apparatus comprising:

a substrate holder which holds thereon a substrate as an object for film formation, said substrate holder having,

a groove section which extends from a portion where said substrate holder contacts said substrate when said substrate holder is holding said substrate to a portion where said substrate holder does not contact said substrate when said substrate holder is holding said substrate[;], and

a porous member which can allow air to pass through [is] provided [in] within said groove section in which the surface of the porous member is at a same level as the surface of substrate holder[,

wherein a surface of the porous member is substantially planar with a top surface of said substrate holder].

19. (Twice Amended) An optical disk substrate film-formation apparatus comprising:

a substrate holder which holds thereon a substrate as an object for film formation, said substrate holder having,

a groove section in a portion where said substrate holder contacts said substrate when said substrate holder is holding said substrate,

a porous member which can allow air to pass through [is] provided [in] within said groove section in which the surface of the porous member is at a same level as the surface of substrate holder[;], and

a through-hole which connects said groove section to the portion where said substrate holder does not contact said substrate when said substrate holder is holding said substrate[,

wherein a surface of the porous member is substantially planar with a top surface of said substrate holder].

73. (Twice Amended) A substrate holder which holds thereon a substrate as an object for film formation in an optical disk substrate film-formation apparatus, said substrate holder comprising:

a groove section which extends from a portion where said substrate holder contacts said substrate when said substrate holder is holding said substrate to a portion where said substrate holder does not contact said substrate when said substrate holder is holding said substrate; and

a porous member which can allow air to pass through [is] provided [in] within said groove section in which the surface of the porous member is at a same level as the surface of substrate holder[,

wherein a surface of the porous member is substantially planar with a top surface of said substrate holder].--